

24th IEEE International Conference on Micro Electro Mechanical Systems

MEMS 2011 CANCUN MEXICO JANUARY 23-27, 2011

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The 24th IEEE International Conference on Micro Electro Mechanical Systems (MEMS 2011) is one of the premier annual events reporting research results on every aspect of microsystems technology. This Conference reflects from the rapid proliferation of the commitment and success of the microsystems research community. In recent years, the IEEE MEMS Conference has attracted more than 700 participants, 800+ abstract submissions and has created the forum to present over 200 select papers in podium and poster/oral sessions. Its single-session format provides ample opportunity for interaction between attendees, presenters and exhibitors. MEMS 2011 will be held in Cancun, Mexico on January 23-27, 2011 at the Hilton Cancun Golf and Spa Resort.

Cancun is situated on the south-east coast of Mexico in the Yucatan Peninsula and historically has beautiful, warm weather in the month of January. White powdery sand beaches and turquoise crystal clear waters together with the famous Mexican hospitality make this a place like no other! The aura of mystery and majesty still lingers around the Mayan ruins and archaeological sites such as Chichen Itza, Tulum and Coba which are all within easy reach of Cancun. Please visit the website for all details as you will not want to miss the pre-and-post conference tours to these areas.

The Hilton Cancun Golf & Spa Resort in Cancun is the host hotel and all sessions will be held in the meeting rooms. The hotel is right on the water and only 15 minutes away from the Cancun International Airport. It is ideally located and close to several of Cancun's top attractions, including historical Mayan archeological sites, premium Championship golf courses, world-class shopping centers and sophisticated dining and entertainment.



Abstract Classification List

- Fabrication and Packaging Technologies
- Materials and Device Characterization
- Design, Simulation, and Theoretical Concepts with Experimental Verification
- Mechanical Sensors and Systems
- Physical MEMS
- RF MEMS
- Biomedical and Chemical Micro Sensors and Systems
- Micro-Fluidic Components and Systems
- Micro-Actuators
- Energy and Power MEMS
- Nano-Electro-Mechanical Devices and Systems

Deadlines

Abstracts Due:
September 14, 2010

Notice of Acceptance:
October 22, 2010

Final Extended Paper Due:
November 22, 2010

Early Bird Registration:
October 31, 2010

CONFERENCE CO-CHAIRS

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